

We claim:

- 1 1. A method for fabricating a tapered optical coupling into a slab waveguide  
2 comprising:  
3 providing a sputtering source;  
4 providing at least one mask between said source and said mask;  
5 disposing a tapered layer of material onto a substrate which includes a  
6 waveguiding layer by means of shadow deposition defined by said sputtering source  
7 and said at least one mask, said tapered layer extending in a first two dimensional  
8 plane and optically coupled to said waveguiding layer; and  
9 photolithographically defining a second taper in said tapered layer, said second  
10 taper extending in a second two dimensional plane intersecting said first two  
11 dimensional plane.
- 1 2. The method of claim 1 where photolithographically defining a second taper in  
2 said tapered layer defines said second two dimensional plane so as to  
3 perpendicularly intersect said first two dimensional plane.
- 1 3. The method of claim 1 further comprising photolithographically defining a slab  
2 waveguide in said waveguiding layer simultaneously with photolithographically  
3 defining a second taper in said tapered layer.

1 4. The method of claim 3 further comprising coupling said slab waveguide to a  
2 photonic crystal.

1 5. The method of claim 4 where coupling said slab waveguide to said photonic  
2 crystal comprises forming said slab waveguide integrally with said photonic crystal.

1 6. The method of claim 1 where disposing said tapered layer of material onto said  
2 substrate comprises disposing said tapered layer by means of shadow deposition  
3 defined by said sputtering source and said at least two masks.

1 7. The method of claim 1 where disposing said tapered layer of material onto said  
2 substrate comprises disposing polycrystalline silicon.

1 8. The method of claim 1 where disposing said tapered layer of material onto said  
2 substrate comprises disposing a material with an approximately matching refractive  
3 index to said waveguiding layer.

1 9. The method of claim 1 further comprising repeating said method on an opposing  
2 side of said substrate to form another tapered optical coupling on said opposing side  
3 aligned with said tapered optical coupling.

1 10. The method of claim 1 further comprising first forming a tapered substrate  
2 by means of shadow deposition and then forming said tapered optical coupling on  
3 said tapered substrate to obtain a fully flared, funnel-shaped, optical coupling.

1 11 A tapered optical coupling comprising:  
2 a substrate;  
3 a slab waveguide on or in said substrate; and  
4 a funnel-shaped termination on or in said substrate and optically coupled to said  
5 slab waveguide.

1 12. The apparatus of claim 11 further comprising a photonic crystal and where  
2 said photonic crystal is optically coupled to said slab waveguide.

1 13. The apparatus of claim 12 where said slab waveguide is integral with said  
2 photonic crystal.

1 14. The apparatus of claim 11 further comprising an optic fiber and where said  
2 funnel-shaped termination is optically coupled to said optic fiber.

1 15. The apparatus of claim 11 where said funnel-shaped termination is formed  
2 by shadow deposition.

1 16. The apparatus of claim 11 where said funnel-shaped termination is  
2 composed of material having an index of refraction approximately matching said slab  
3 waveguide.

1 17. The apparatus of claim 16 where said funnel-shaped termination is  
2 composed of polycrystalline silicon.

1 18. The apparatus of claim 17 where said slab waveguide is composed of  
2 GaAs.

1 19. The apparatus of claim 11 where said funnel-shaped termination is a half-  
2 funnel shape.

1 20. The apparatus of claim 11 where said funnel-shaped termination is a full-  
2 funnel shape.

1 21. The apparatus of claim 11 where said funnel-shaped termination  
2 comprises a surface for optical coupling inclined with respect to said substrate.